

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Young Hoon PARK, et al.

FOR: APPARATUS AND METHOD FOR DEPOSITING THIN FILM ON WAFER  
USING REMOTE PLASMA

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Prior to the Examiner acting in the above-referenced application, please  
preliminary amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 2  
of this paper.

**Remarks** begin on page 6 of this paper.